

Combined Analysis for the characterisation of texture, microstructure and stresses of nanocrystalline thin layers

M. Morales, Daniel Chateigner, L. Lutterotti
CIMAP, CRISMAT-ENSICAEN, France
DIM-Univ Trento, Italia

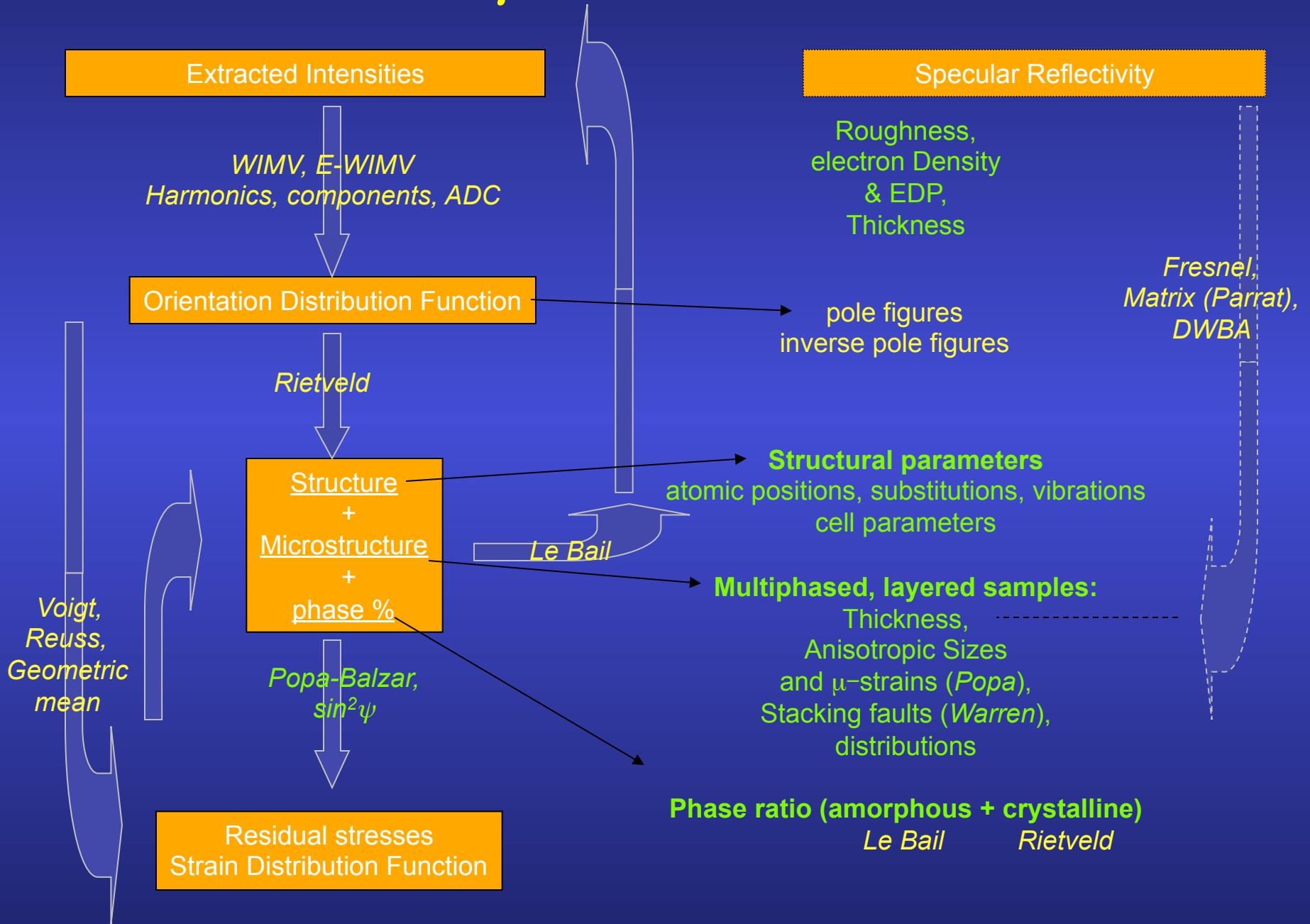
ZnSe films

nano-Si films

AlN/Pt/Ni(Co) films

Irradiated FAp ceramics

Implemented codes



Rietveld

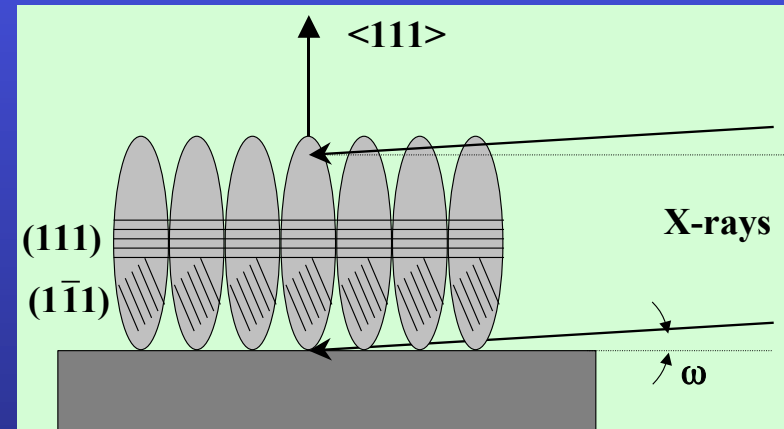
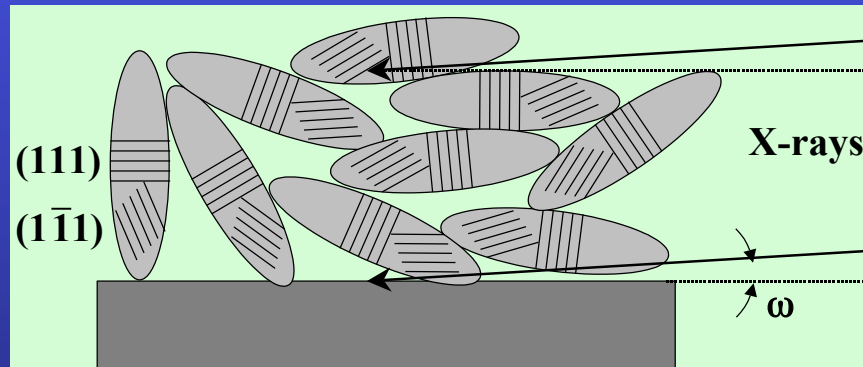
$$I_i^{calc}(\chi, \phi) = \sum_{n=1}^{N_{phases}} S_n \sum_k L_k |F_{k;n}|^2 S(2\theta_i - 2\theta_{k;n}) P_{k;n}(\chi, \phi) A + bkg_i$$

Texture

$$P_k(\chi, \phi) = \int_{\varphi} f(g, \varphi) d\varphi$$

- ODF solved using E-WIMV, Standard functions, Harmonics, ADC or max entropy

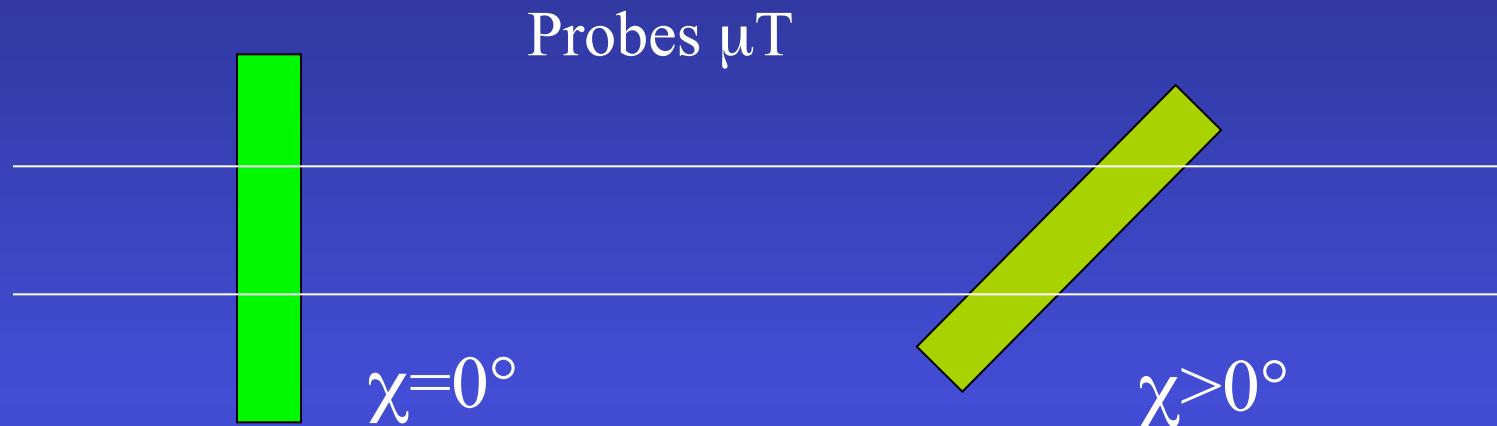
Anisotropic sizes and microstrains



- Texture helps the "real" mean shape determination
- Determination by peak deconvolution + Popa formalism

Layering

$$C_{\chi}^{\text{top film}} = g_1 (1 - \exp(-\mu T g_2 / \cos \chi)) / (1 - \exp(-2\mu T / \sin \omega \cos \chi))$$



Strain-Stress

- Using the ODF and geometric mean approach
- Fitting the macrostress tensor

Si nanocrystalline thin films

Deposition: reactive magnetron sputtering (H_2 / Ar)

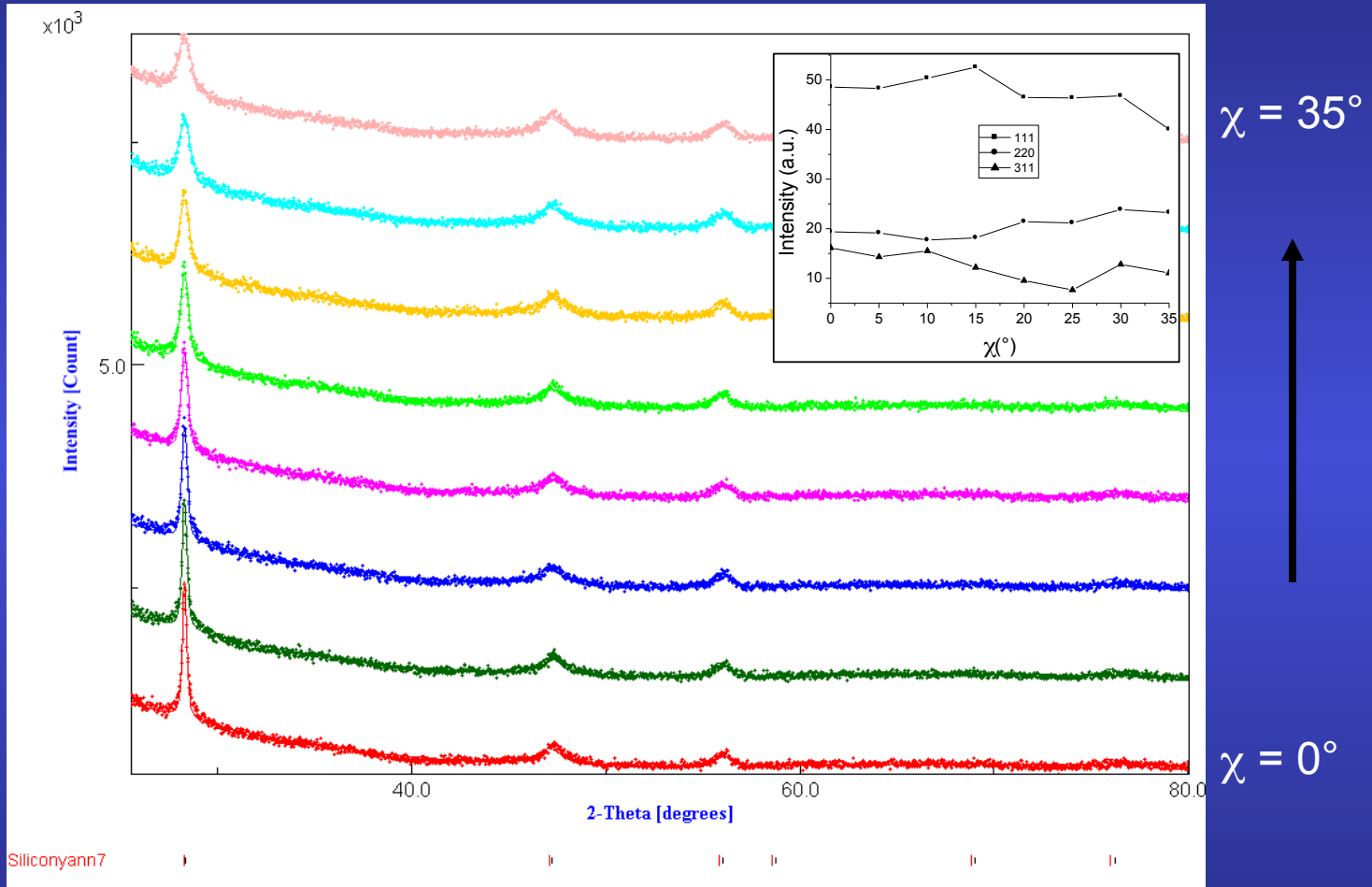
Low temperature: 200°C

Substrates: amorphous SiO_2 (a- SiO_2) and (100)-Si single-crystals

Varying Target-substrate distance (d)

Aim: quantum confinement, photoluminescence properties

Typical refinement

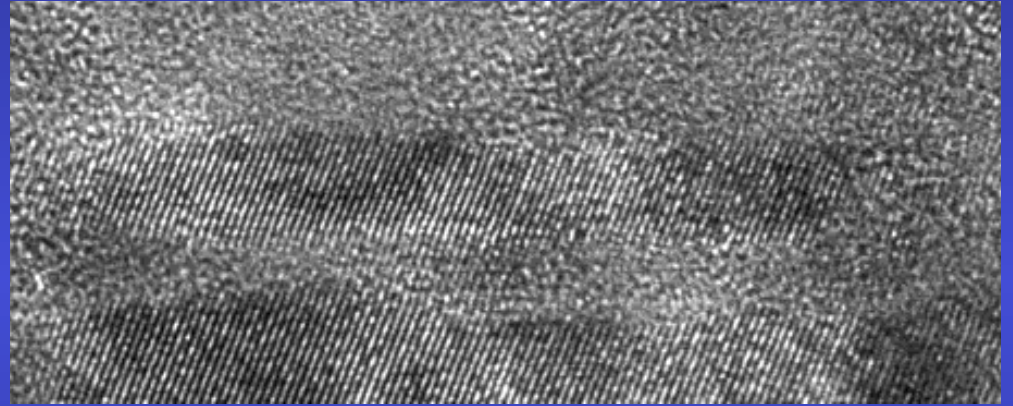
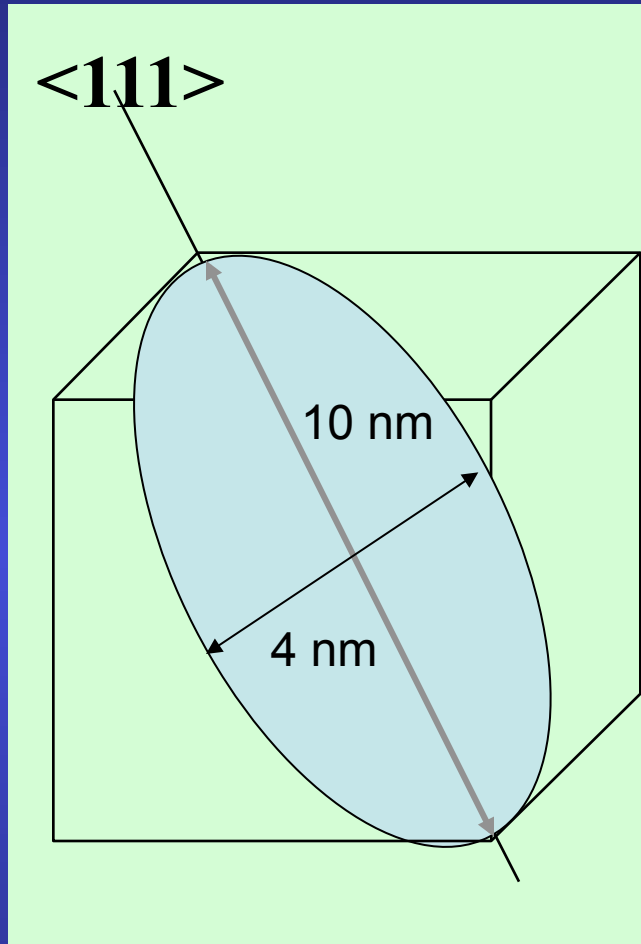


broad, anisotropic diffracted lines, textured samples

Refinement Results

Sample	d (cm)	a (Å)	RX thickness (nm)	Anisotropic sizes (Å)			Texture parameters			Reliability factors (%)			
				<111>	<220>	<311>	Maximum (m.r.d.)	minimum (m.r.d.)	Texture index F ² (m.r.d ²)	RP ₀	R _w	R _B	R _{exp}
A	4	5.4466 (3)	—	94	20	27	1.95	0.4	1.12	1.72	4.0	3.7	3.5
B	6	5.4439 (2)	711 (50)	101	20	22	1.39	0.79	1.01	0.71	4.9	4.3	4.2
C	7	5.4346 (4)	519 (60)	99	40	52	1.72	0.66	1.05	0.78	4.3	4.0	3.9
D	8	5.4461 (2)	1447 (66)	100	22	33	1.57	0.63	1.04	0.90	5.5	4.6	4.5
E	10	5.4462 (2)	1360 (80)	98	20	25	1.22	0.82	1.01	0.56	5.0	3.9	4.0
F	12	5.4452 (3)	1110 (57)	85	22	26	1.59	0.45	1.05	1.08	4.2	3.5	3.7
G	6	5.4387 (3)	1307 (50)	89	22	28	1.84	0.71	1.01	1.57	5.2	4.7	4.2
H	12	5.4434 (2)	1214 (18)	88	22	24	2.77	0.50	1.12	2.97	5.0	4.5	4.3

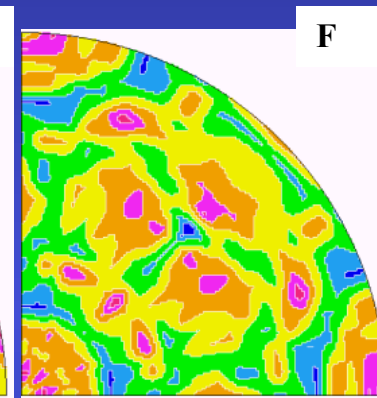
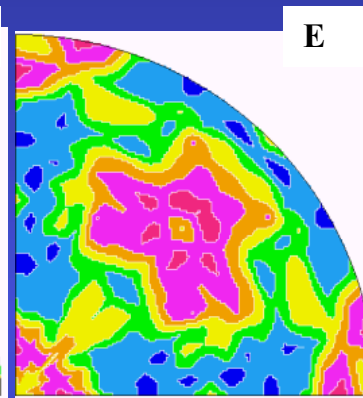
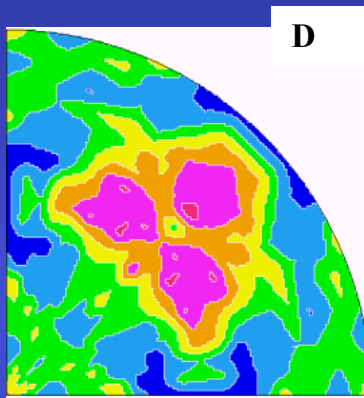
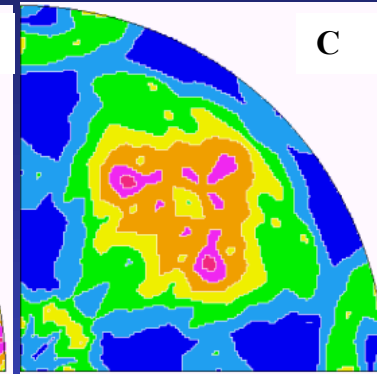
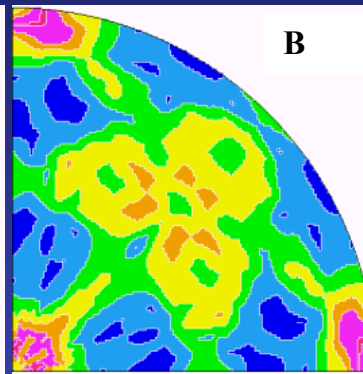
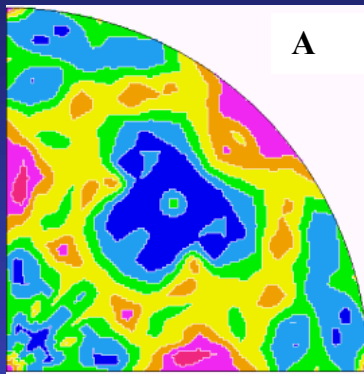
Mean anisotropic shape



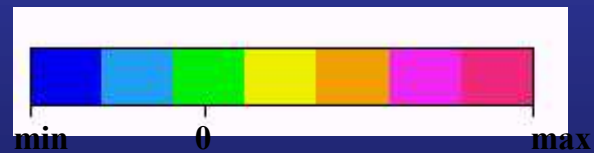
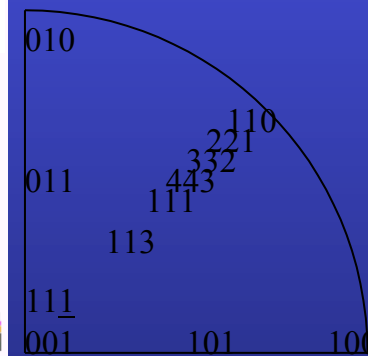
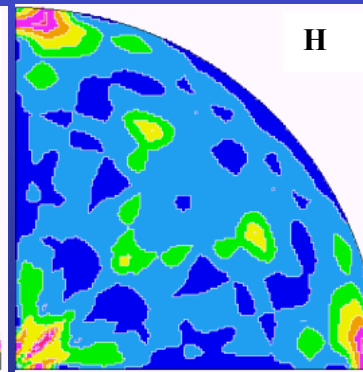
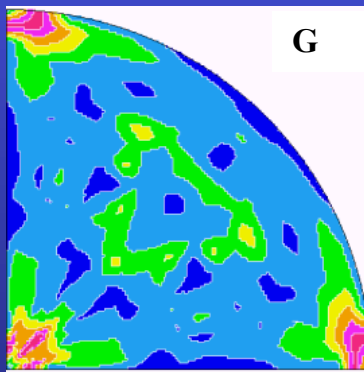
Schematic of the mean crystallite shape for Sample D represented in a cubic cell, as refined using the Popa approach and exhibiting a strong elongation along $\langle 111 \rangle$, and TEM image

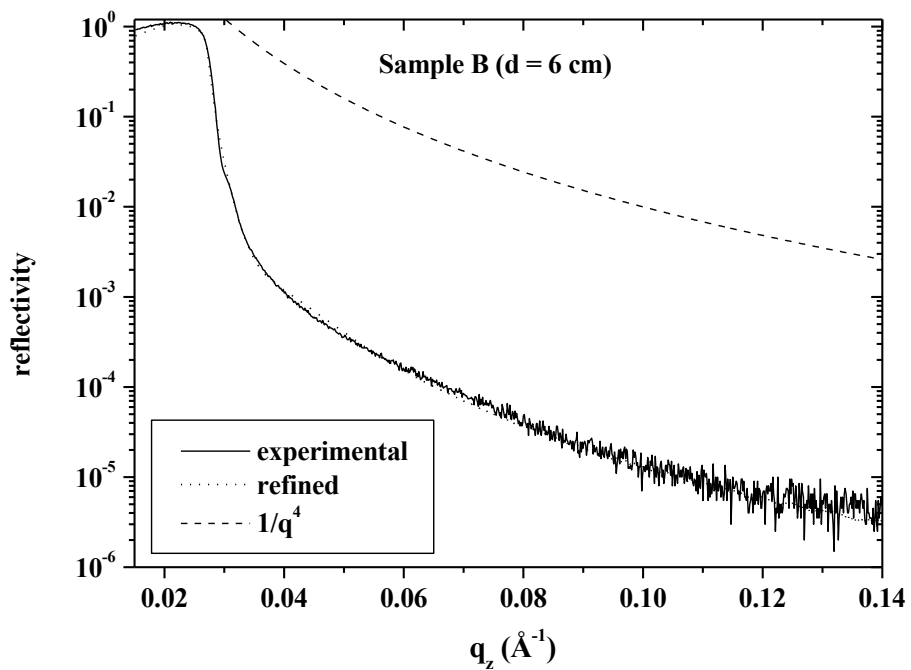
001 Inverse Pole Figures

a-SiO₂



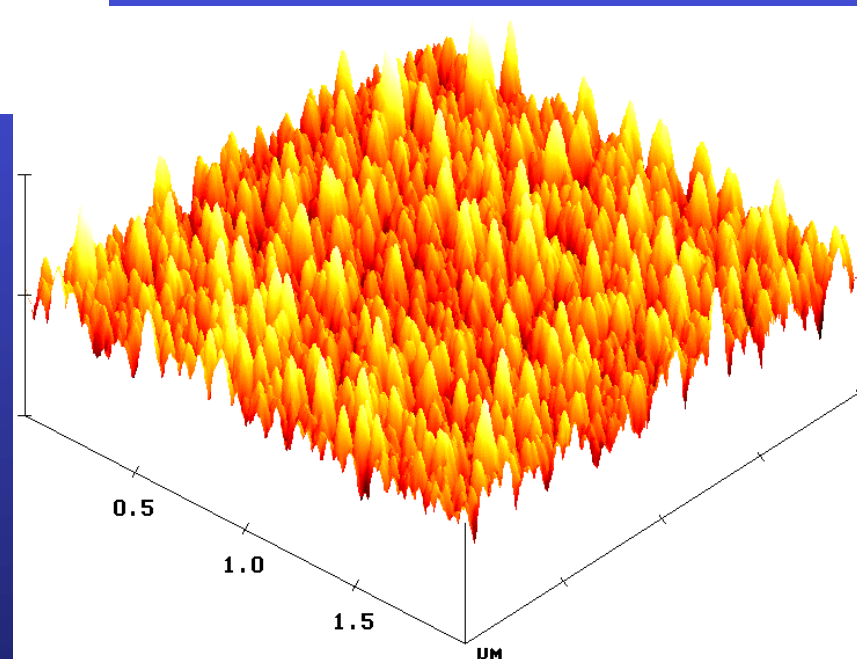
(100)-Si

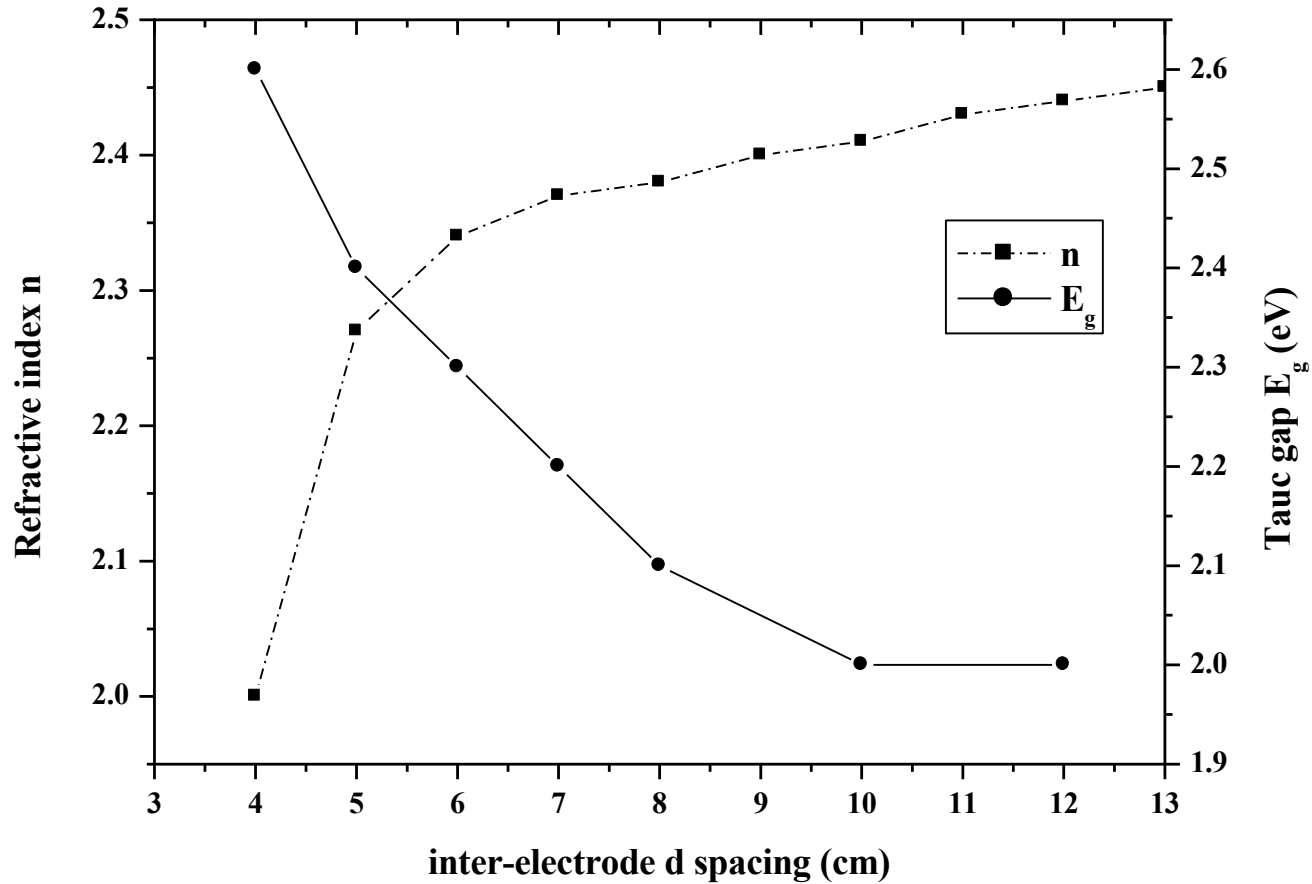




XRR:
Roughness
governed

AFM:
homogeneous
roughness





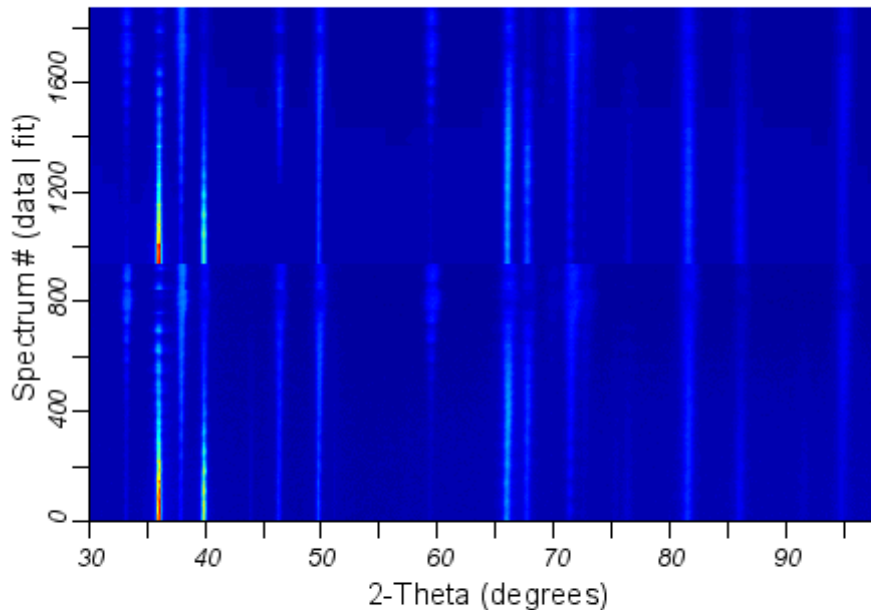
↪ Refractive index linked to film porosities:
 Larger target-sample distances: increased compacity due to lower
 nanopowder filling

AIN/Pt/TiO_x/Al₂O₃/Ni-Co-Cr-Al

E. Derniaux, PhD

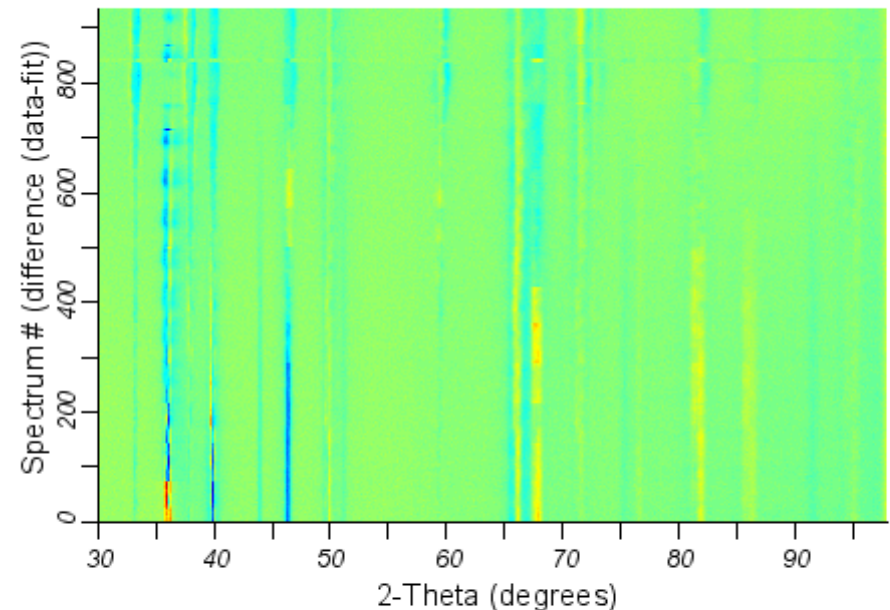
2D Multiplot for Data 05_37P64

measured data and fit



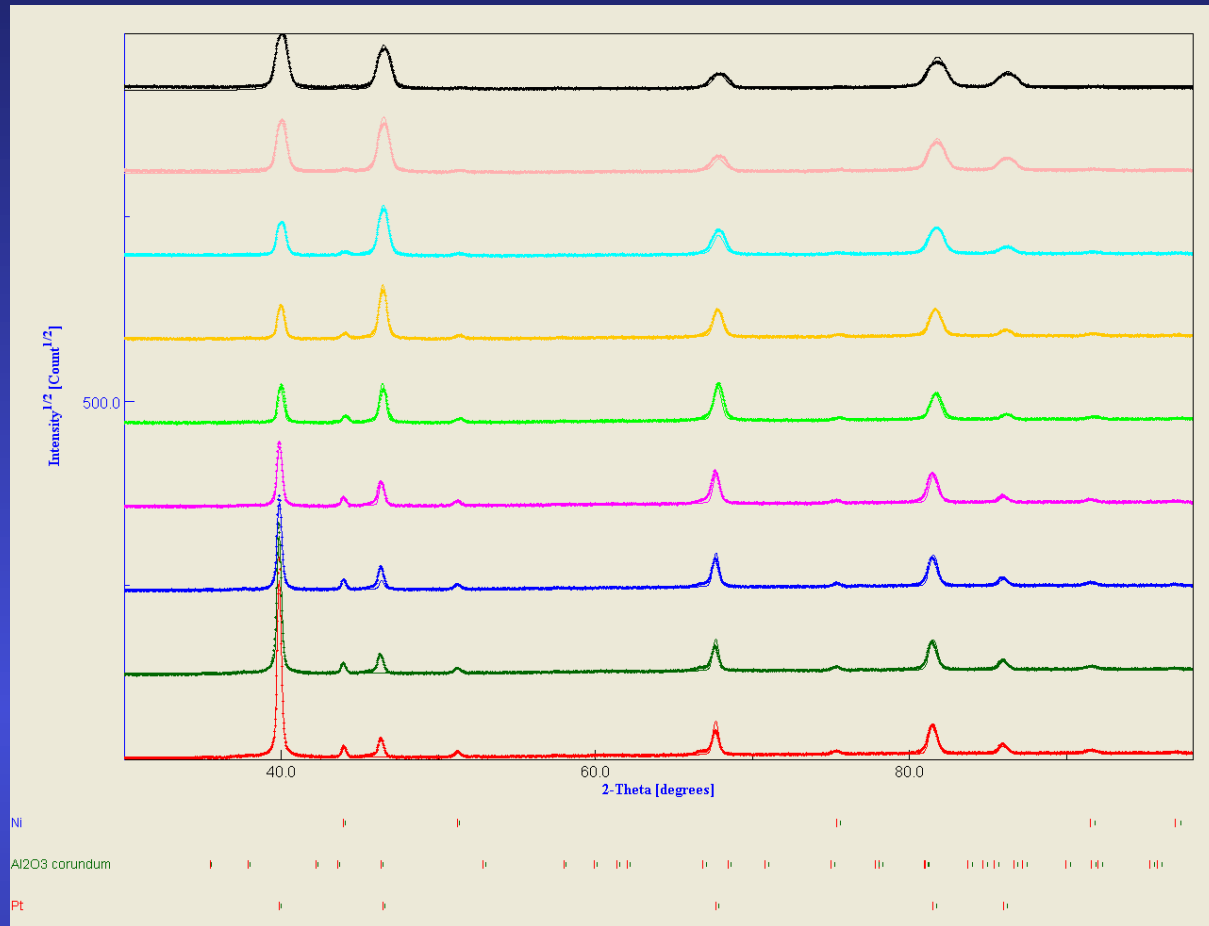
2D difference plot for Data 05_37P64

difference data - fit

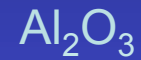


Rw (%) = 24.120445
Rexp (%) = 5.8517213

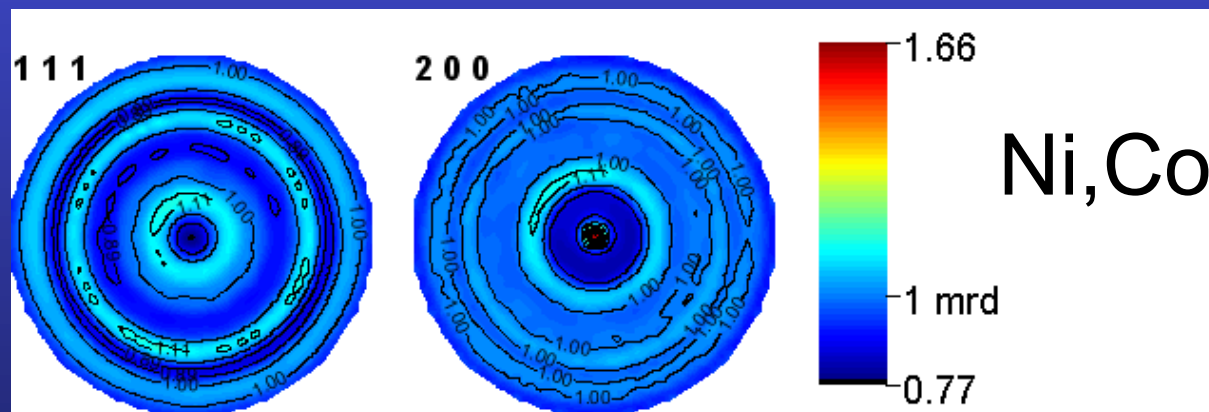
T(AIN) = 14270(3) nm
T(Pt) = 430(3) nm



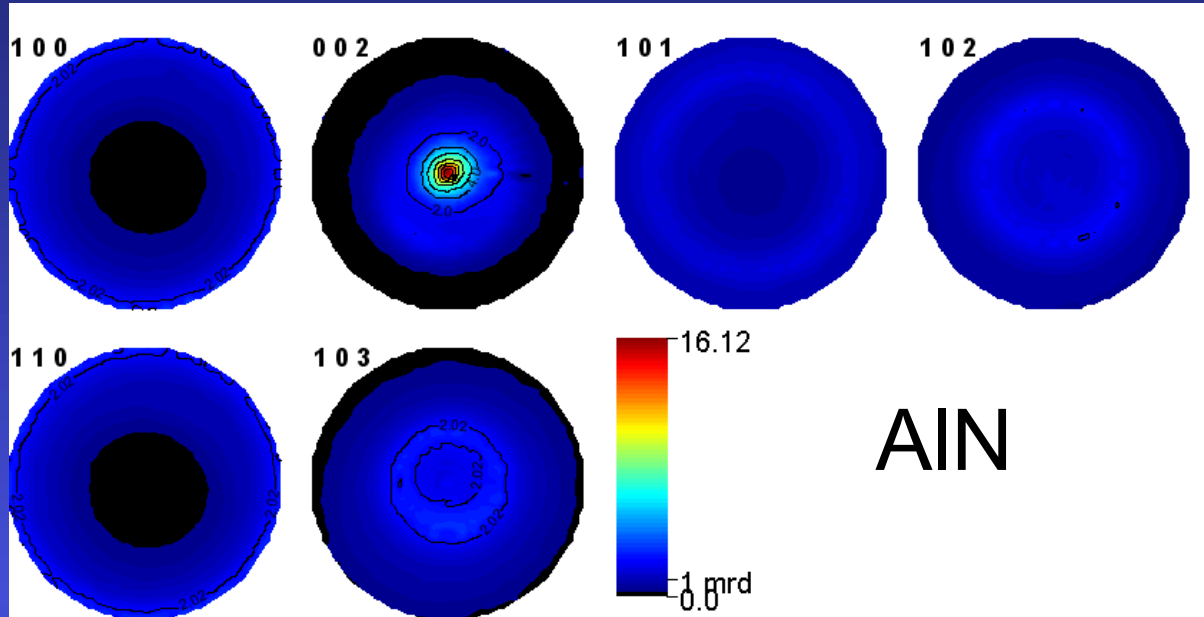
(χ, φ) randomly
selected diagrams



$a = 4.7562(6) \text{ \AA}$
 $c = 12.875(3) \text{ \AA}$
 $T = 7790(31) \text{ nm}$
 $\langle t \rangle = 150(2) \text{ \AA}$
 $\langle \varepsilon \rangle = 0.008(3)$



$a = 3.569377(5) \text{ \AA}$
 $\langle t \rangle = 7600(1900) \text{ \AA}$
 $\langle \varepsilon \rangle = 0.00236(3)$
 $\sigma_{11} = -328(8) \text{ MPa}$
 $\sigma_{22} = -411(9) \text{ MPa}$



Rw (%) = 4.1

$a = 3.11203(1) \text{ \AA}$

$c = 4.98252(1) \text{ \AA}$

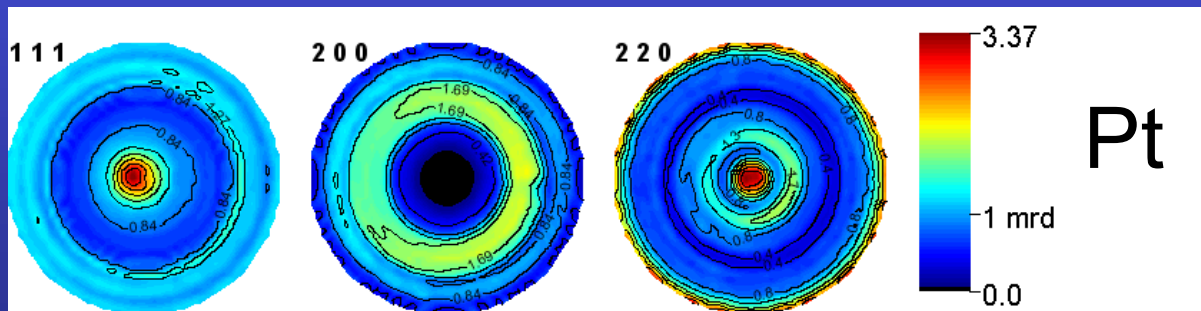
$T = 14270(3) \text{ nm}$

$\langle t \rangle = 2404(8) \text{ \AA}$

$\langle \varepsilon \rangle = 0.001853(2)$

$\sigma_{11} = -1019(2) \text{ MPa}$

$\sigma_{22} = -845(2) \text{ MPa}$



Rw (%) = 33.3

$a = 3.91198(1) \text{ \AA}$

$T = 1204(3) \text{ nm}$

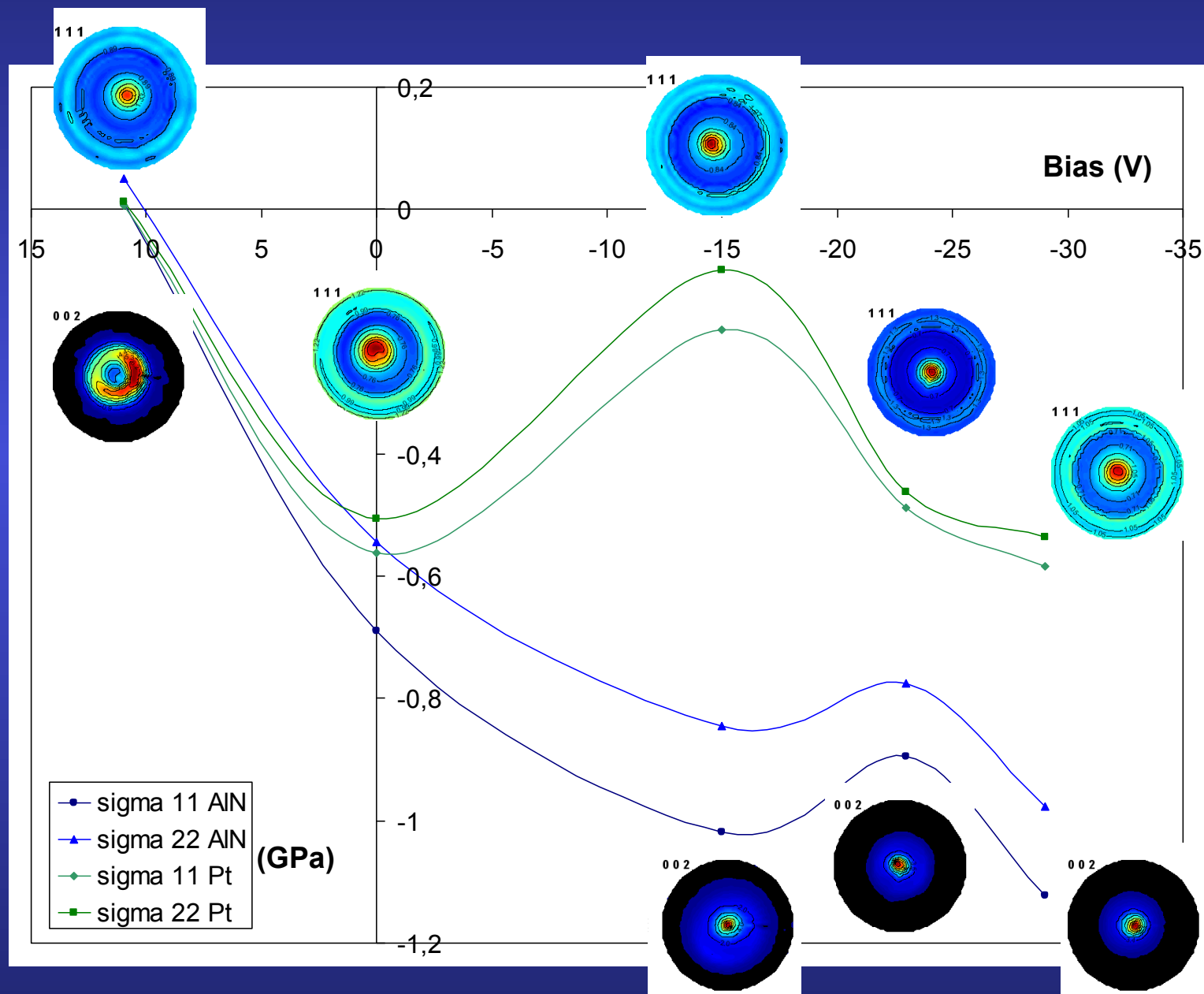
$\langle t \rangle = 2173(10) \text{ \AA}$

$\langle \varepsilon \rangle = 0.002410(3)$

$\sigma_{11} = -196.5(8)$

$\sigma_{22} = -99.6(6)$

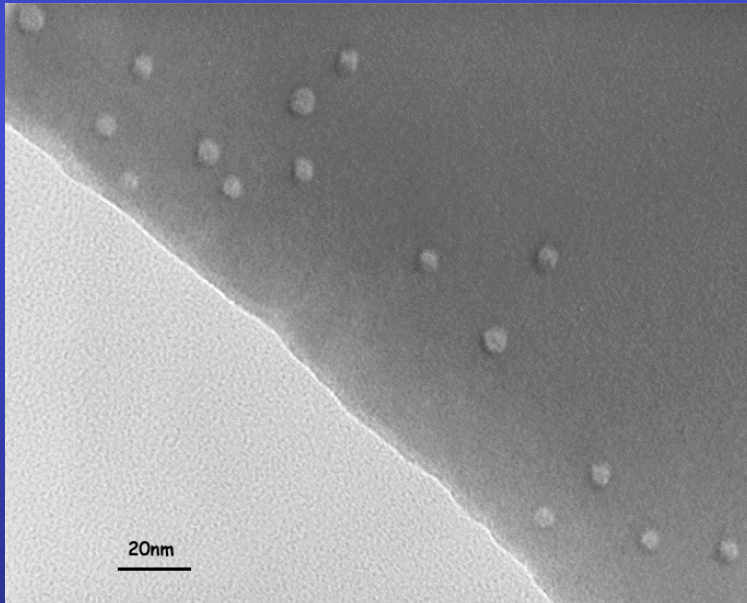
Substrate bias vs stress-texture evolution



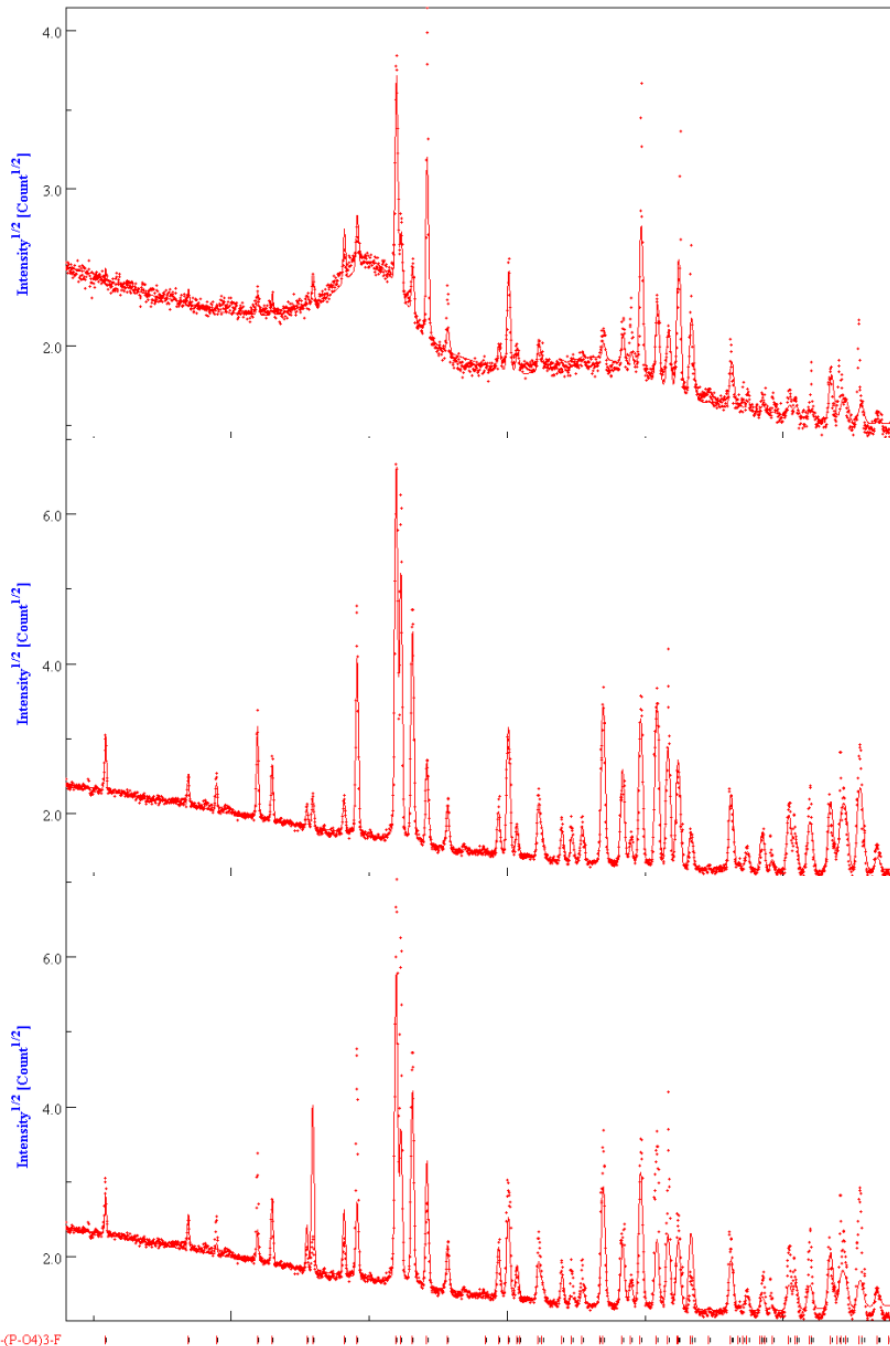
Irradiated FluorApatite (FAp) ceramics

S. Miro, PhD

Self-recrystallisation under irradiation, depending on $\text{SiO}_4 / \text{PO}_4$ ratio (FAp / Nd-Britholite) and on irradiating species



TEM of FAp
irradiated with 70
MeV, 10^{12} Kr cm^{-2}
ions



texture corrected,
 10^{13} Kr cm⁻²

Virgin, with texture
correction

Virgin, no texture
correction

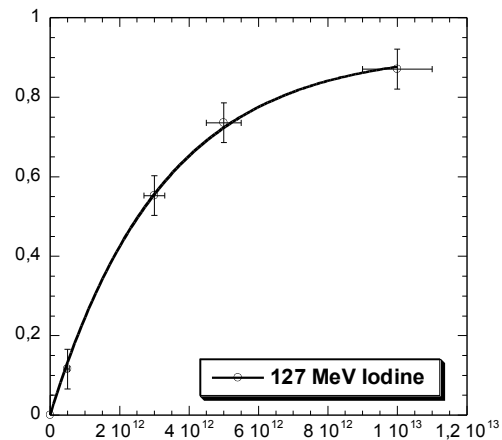
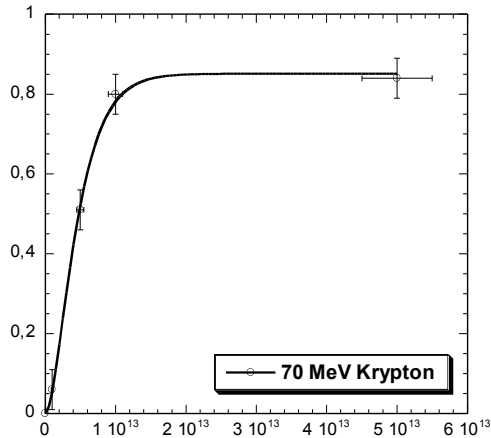
Fluence (ions.cm ⁻²)	Vc/V (%)	A (Å)	c (Å)	<t> (nm)	Δ _a /a ₀ (%)	Δ _c /c ₀ (%)	R _w (%)	R _B (%)
0	100	9.3365(3)	6,8560(5)	294(22)	-	-	14.6	9.1
Kr								
10 ¹¹	100	-	-	-	-	-		
10 ¹²	100	-	-	-	-	-		
5.10 ¹²	49(1)	9.3775(9)	6.8912(8)	294(20)	0.44	0.53	24	15
10 ¹³	20(1)	9.4236(5)	6.9105(5)	291(20)	0.94	0.82	9.9	6
5.10 ¹³	14(1)	9.3160(4)	6.8402(5)	294(22)	-0.21	-0.22	10.5	5.9
I								
10 ¹¹	-	-	-	-	-	-		
5.10 ¹¹	86(2)	9.3603(3)	6.8790(5)	90(10)	0.26	0.35	23.9	15.1
10 ¹²	-	-	-	-	-	-		
3.10 ¹²	47(2)	9.3645(3)	6.8840(5)	91(6)	0.30	0.42	13.3	9
5.10 ¹²	29.2(5)	9.3765(5)	6.8881(6)	77(11)	0.44	0.48	10.4	7.3
10 ¹³	13.2(2)	9.3719(4)	6.8857(6)	82(9)	0.38	0.45	6.7	4.9

Single impact model associated to crystal size reduction

Cell parameters and volume increase, then relax

Amorphisation / recrystallisation competition: single or double impact

Amorphous/crystalline volume fraction (damaged fraction $F_d = V_a / V$) as determined by x-ray diffraction



B

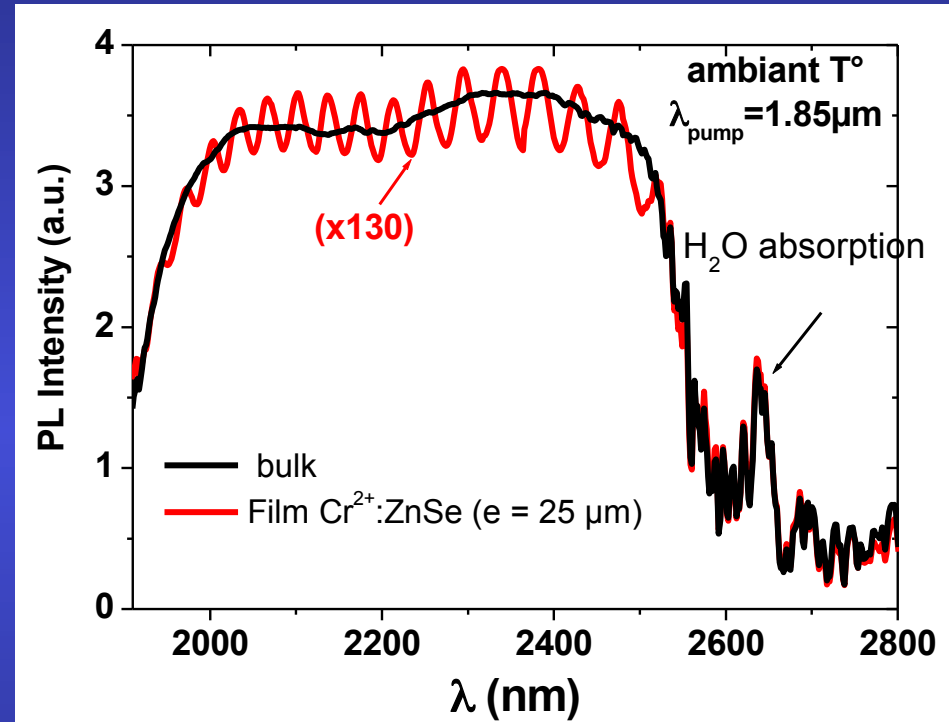
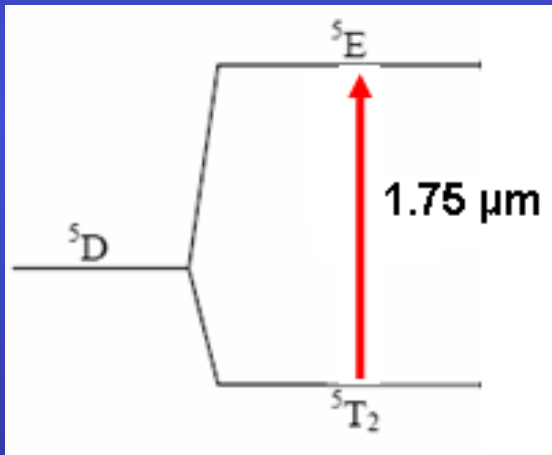
Fitting parameters	Krypton		Iodine
	Single impact $F_d = B(1 - \exp(-A\phi t))$	Double impact $F_d = B(1 - (1 + A\phi t) \exp(-A\phi t))$	Single impact $F_d = B(1 - \exp(-A\phi t))$
$A = \pi R^2$ (cm ²)	$1.85 \pm 0.15 \cdot 10^{-13}$	$4.1 \pm 0.15 \cdot 10^{-13}$	$3.3 \pm 0.15 \cdot 10^{-13}$
Radius R (nm)	2.4 ± 0.2	3.6	3.2
B (Max.damage rate)	0.87	0.85 ± 0.2	0.92 ± 0.2
χ^2	0.013	0.0006	0.0004

ZnSe:Cr²⁺ films

N. Vivet, PhD

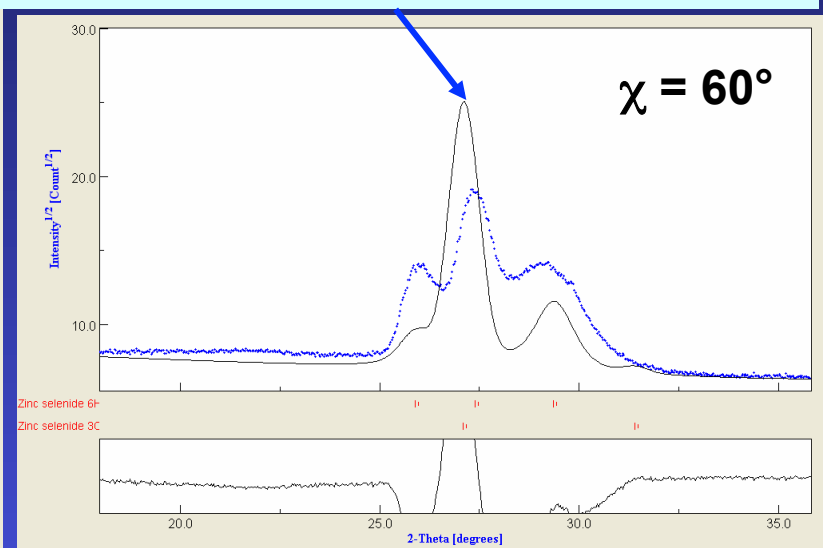
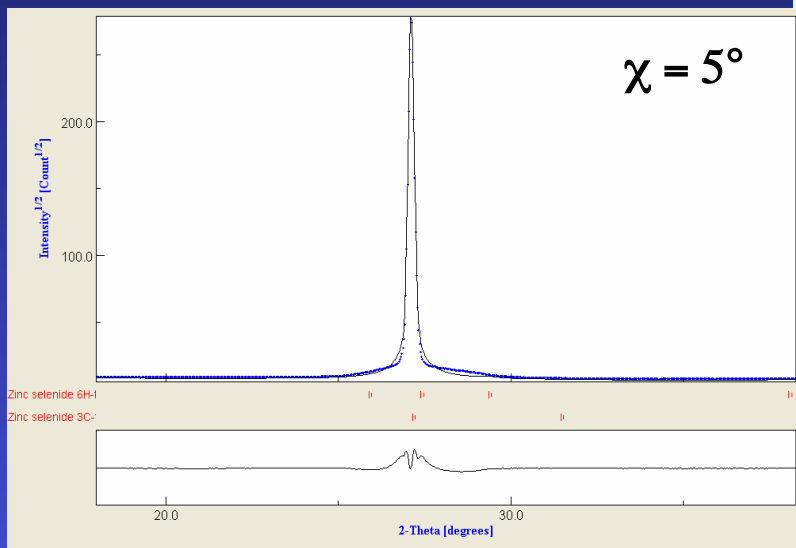
conditions:

- ◆ $20 \leq T_d \leq 385^\circ\text{C}$
- ◆ $P_{\text{RF}} = 50\text{-}200\text{W}$
- ◆ $P_{\text{Ar}} = 0.5\text{ Pa and } 2\text{ Pa}$
- ◆ $d = 7\text{ and } 10\text{ cm}$

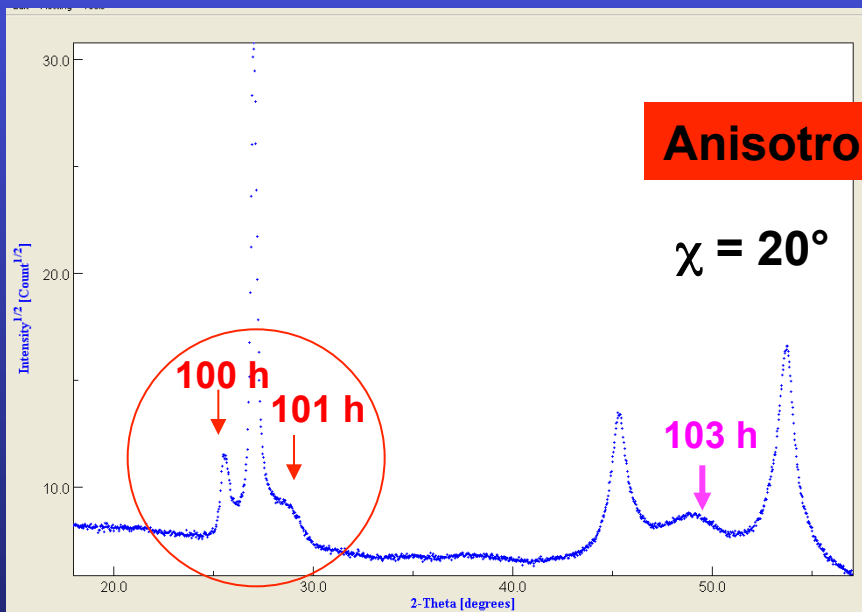


- ◆ Large emission band centred at 2200nm: $^5E \rightarrow ^5T_2$ transition (Cr²⁺)
- ◆ Single crystals and thin films: similar spectra

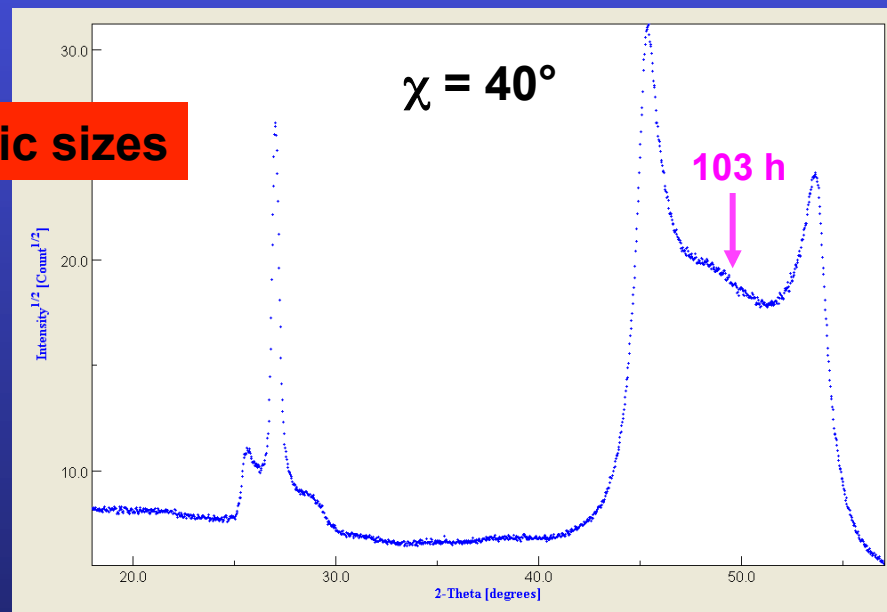
111 Peak shifts



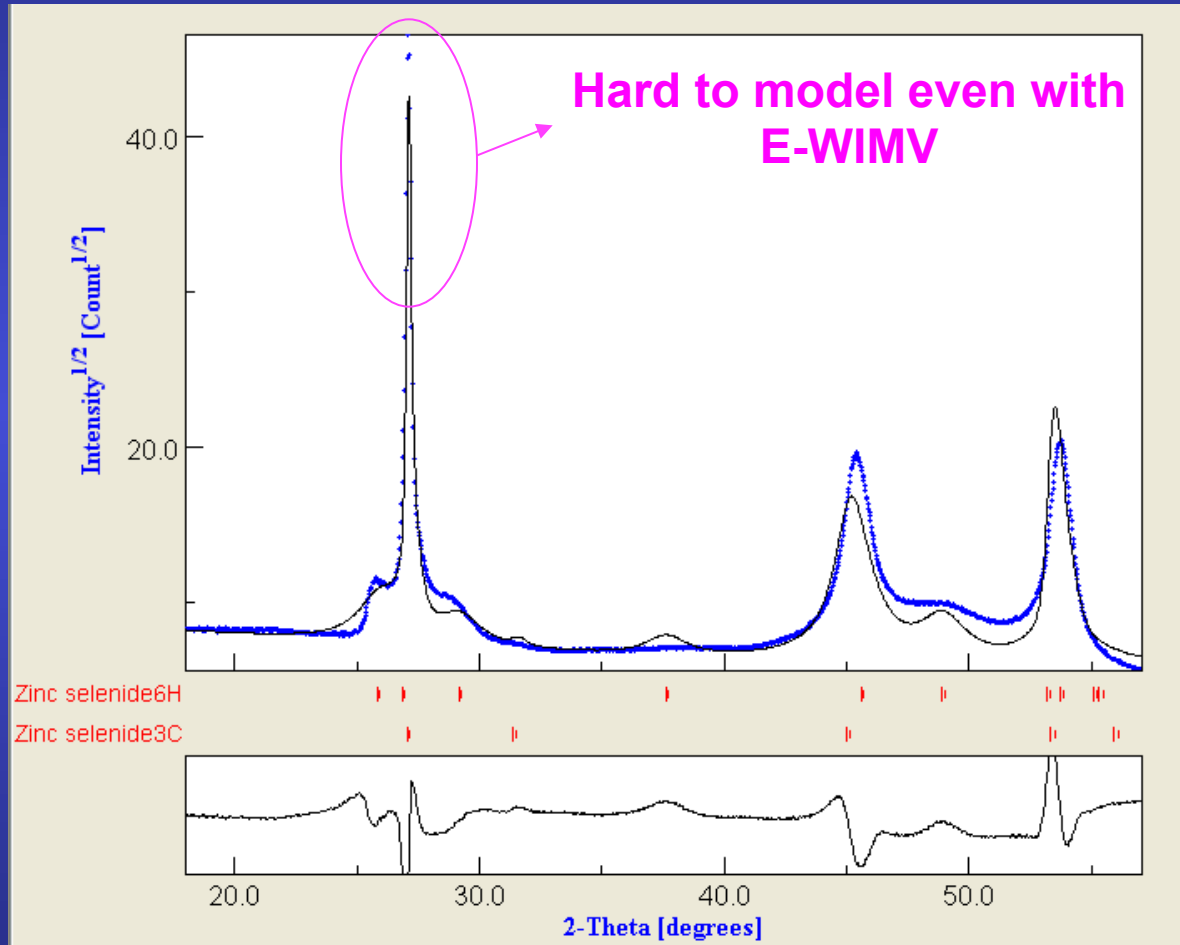
Residual stresses and/or stacking faults



Anisotropic sizes



Fibre Texture + 2 polytypes (6H and 3C) + anisotropic sizes + residual stresses and/or stacking faults + layering



Sum diagram: $\omega = 13.65^\circ$, $P_{RF} = 200W$

Conclusions

- a) Texture affects phase ratio and structure determination
- b) Microstructure (crystallite size) affects texture (go to a)
- c) Stresses shift peaks then affects structure and texture determination
- d) Combined analysis may be a solution, unless you can destroy your sample or are not interested in macroscopic anisotropy ...
- e) If you think you can destroy it, perhaps think twice
- f) more information is always needed: local probes ...
- g) www.ecole.ensicaen.fr/~chateign/texture/combined.pdf